

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
MIKI OGAWA, ET AL.) : Examiner: Unassigned
Application No.: 10/535,452) : Group Art Unit: 3637
Filed: May 19, 2005) : Confirmation No.: 7240
For: COLUMNAR STRUCTURED) : September 15, 2006
MATERIAL AND METHOD OF :
MANUFACTURING THE SAME)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

FIRST SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the document listed on the enclosed Form PTO-1449. A copy of the listed document is also enclosed.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that an initialed copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

/Scott D. Malpede/

Scott D. Malpede
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ATTY DOCKET NO.
03500.017774APPLICATION NO.
10/535,452

APPLICANTS

MIKI OGAWA, ET AL.

FILING DATE

May 19, 2005GROUP
3637

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

		M. Haupt, et al., "Semiconductor Nanostructures Defined with Self-Organizing Polymers", Journal of Applied Physics, Vol. 91, No. 9, pp. 6057-6059 (May 1, 2002).

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.